

PATENT  
1691-0177PUS2

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Hiroyuki FUKUYAMA et al. Conf.:

Appl. No.: New Group:

Filed: March 26, 2004 Examiner:

For: SINGLE CRYSTALLINE ALUMINUM NITRIDE  
FILM, METHOD OF FORMING THE SAME, BASE  
SUBSTRATE FOR GROUP III ELEMENT NITRIDE  
FILM, LIGHT EMITTING DEVICE AND SURFACE  
ACOUSTIC WAVE DEVICE

INFORMATION DISCLOSURE STATEMENT  
(SUBMISSION WITH CONTINUATION-IN-PART OR  
RULE 1.53(b) CONTINUATION OR DIVISIONAL APPLICATION)

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

March 26, 2004

Sir:

Pursuant to 37 C.F.R. §§ 1.97 and 1.98, Applicant(s) hereby submit(s) an Information Disclosure Statement for consideration by the Examiner.

I. LIST OF PATENTS, PUBLICATIONS OR OTHER INFORMATION

The patents, publications, or other information submitted for consideration by the Office are listed on the PTO-1449 form(s), attached hereto.

II. REFERENCES PREVIOUSLY CITED OR SUBMITTED

Pursuant to 37 C.F.R. § 1.98(d), consideration of information listed on the PTO-1449 form(s) is requested since any patents, publications, or other information which are listed on the PTO-1449 form(s) but for which copies are not enclosed herewith, were previously cited by or submitted to the PTO in one of the following applications which has been relied upon for an earlier filing date under 35 U.S.C. § 120:

U.S. Appl. No(s).  
10/247,539

U.S. Filing Date(s)  
September 20, 2002

III. FEES

This Information Disclosure Statement is being filed concurrent with the filing of a continuation-in-part, continuation, or divisional patent application; therefore, no fee is required.

If the Examiner has any questions concerning this IDS or requires a copy of any of the references cited but not provided, he/she is requested to contact the undersigned. If it is determined that this IDS has been filed under the wrong rule, the PTO is requested to consider this IDS under the proper rule and charge the appropriate fee to Deposit Account No. 02-2448.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to Deposit Account No. 02-2448 for any additional fee required under 37 C.F.R. §§ 1.16 or 1.17; particularly, extension of time fees.

Respectfully submitted,

BIRCH, STEWART, KOLASCH & BIRCH, LLP

By marc 19 Dec 06  
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Attachment(s):  PTO-1449(s)

- References - (1) document
- Foreign Search Report
- Other:

(Rev. 02/12/2004)

Form PTO-1449

**INFORMATION DISCLOSURE CITATION  
IN AN APPLICATION**

(Use several sheets if necessary)

ATTY. DOCKET NO.

1691-0177PUS2

APPLICATION NO.

NEW

APPLICANT

Hiroyuki FUKUYAMA et al.

FILING DATE

March 26, 2004

GROUP

**U.S. PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	Kind	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	US 5,741,724	A	1998-04-21	Ramdani et al.			
	US						
	US						
	US						
	US						
	US						
	US						
	US						
	US						

**FOREIGN PATENT DOCUMENTS**

Office	DOCUMENT NUMBER	Kind	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION	
							YES	NO
JP	2-141495	A	1990-05-30	JAPAN			Abs	
JP	2-153897	A	1990-06-13	JAPAN			Abs	

**OTHER DOCUMENTS** (Include Name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.)

T. SHIBATA et al., "Characterization of high-quality epitaxial AlN films grown by MOVPE", Mat. Res. Soc. Symp. Proc., Vol. 693, 2002, pp. I9.3.1-I9.3.4, Material Research Society.

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.